Docket No.:0756-7244

APR 0 5 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

n re PATENT application of	. )	
Koichiro TANAKA, et al.	)	
Serial No. 10/749,505	)	Group Art Unit: 2828
Filed: January 2, 2004	)	Examiner: A. Rodriguez
For: LASER IRRADIATION METHOD, METHOD	)	
FOR MANUFACTURING SEMICONDUCTOR	)	
DEVICE, AND LASER IRRADIATION SYSTEM	•	

## **CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with The United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P. O. Box 1450, Alexandria VA 22313-1450, on Paper V1, 2006

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## THIRD REQUEST FOR STATUS

Honorable Commissioner of Patents

P. O. Box 1450

Alexandria VA 22313-1450

Sir:

To date the undersigned attorney of record has received no action in the aboveidentified patent application. Please provide the undersigned with a status report of the application in writing.

Respectfully submitted,

Eric J. Robinson

Reg. No. 38,285

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PMB 955

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